

Use of ^{19}F NMR Spectroscopy in Silicon Solar Cell Fabrication

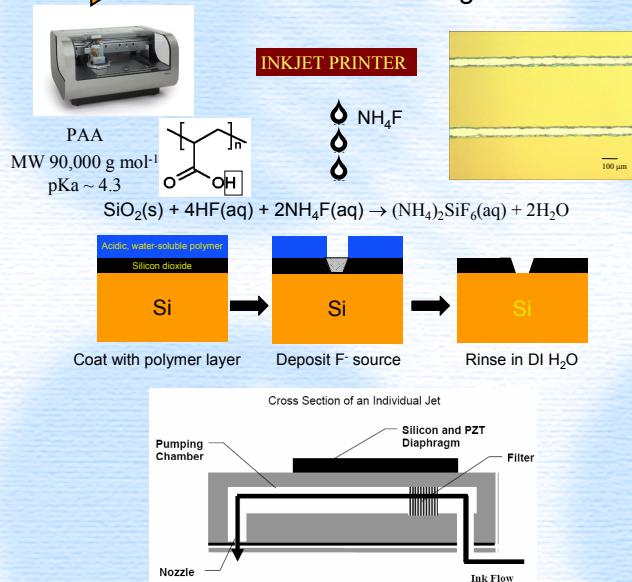
A. Lennon¹, S. Wenham¹, and J. Hook²

¹ARC Photovoltaics Centre of Excellence, and ²NMR Facility, Analytical Centre, The University of New South Wales, Sydney 2052, Australia

BACKGROUND

- Efficiencies of laboratory-fabricated silicon solar cells (25%)^{1,2} exceed those of commercial cells (16-18%).
- Need to replace photolithographic dielectric patterning processes (used by the high efficiency laboratory cells) with cheaper process such as inkjet printing.

→ Maskless Patterned Etching method.³

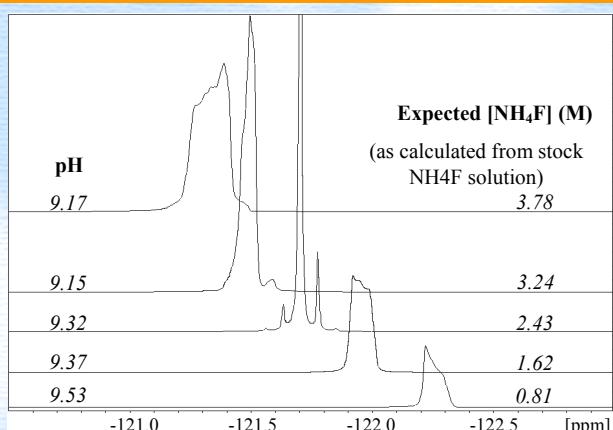


FUJIFILM Dimatix DMP-2831 piezoelectric inkjet printhead.

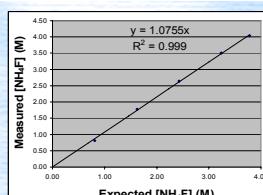
OBJECTIVES

- To quantify fluoride species in solution before and after the jetting (printing) process.
- To determine whether etching of SiO_2 in the silicon printheads occurs by detection of etch products (e.g., SiF_6^{2-}) in the solution after jetting,

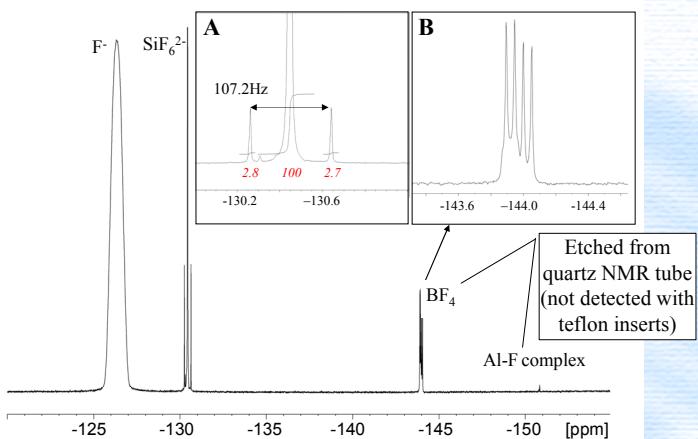
QUANTIFICATION OF FLUORIDE SOLUTIONS



^{19}F NMR spectra of NH_4F solutions containing 20% (v/v) PEG 400. Sodium trifluoroacetate (TFA; ~80 mM in D_2O) was added as a quantitation standard.

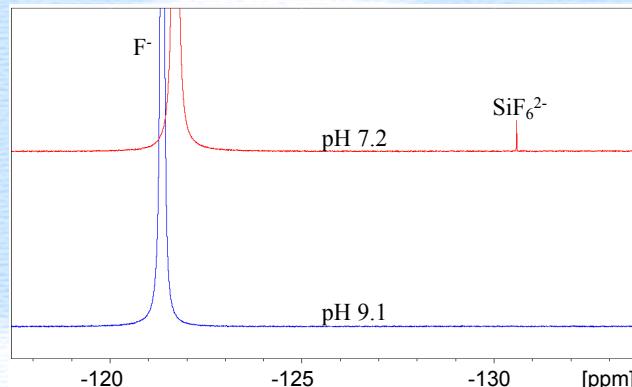


SPECTRAL IDENTIFICATION OF ETCH PRODUCTS



^{19}F NMR spectrum was recorded for a dilute HF/ NH_4F solution which had been used to etch a 300 nm thick oxide layer from a silicon wafer (etching supernatant).

DETECTION OF ETCHING IN JETTED SOLUTIONS



^{19}F NMR spectra (using teflon inserts) of solutions collected from the print head nozzles (i.e., after jetting).

Sample	$\text{pH } 7.2$		$\text{pH } 9.1$	
	$[\text{F}^-] (\text{M})$	$[\text{SiF}_6^{2-}] (\text{mM})$	$[\text{F}^-] (\text{M})$	$[\text{SiF}_6^{2-}] (\text{mM})$
Before jetting	3.45	-	3.23	-
After jetting	3.75	1.1 ¹	3.97 ²	-

¹ Number of firing nozzles and duration of collection time were not controlled.

² Increased $[\text{F}^-]$ likely due to dehydration and thus depended on collection time.

CONCLUSIONS

- ^{19}F NMR was used to detect etching of SiO_2 in silicon printheads by NH_4F solutions.
- This etching can be reduced by raising the pH of the NH_4F jetting solution from 7.2 to 9.1.
- NMR spectroscopy may be a useful way to characterise jetting processes, however controlled collection of jetting samples is required for quantitative interpretation.

REFERENCES

- Zhao, J., Wang, A. and Green, M. (1999) *Prog. Photovolt. Res.*, **7**, 471-474.
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- Lennon, A., Utama, R., Ho-Baillie, A. and Wenham, S. (2008) *Proc. of the Digital Fabrication Conference*, Pittsburgh, 251-255.